

Notice of Allowability

Application No.

10/636,076

Examiner

Sheela C. Chawan

Applicant(s)

LIN ET AL.

Art Unit

2624

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address--

All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. **THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS.** This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.

1. ☒ This communication is responsive to 7/27/07.
2. ☒ The allowed claim(s) is/are 1-3,5,9,13 and 15-28, Renumber as 1-20.
3. ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All b) ☐ Some* c) ☐ None of the:
1. ☐ Certified copies of the priority documents have been received.
2. ☐ Certified copies of the priority documents have been received in Application No. _____.
3. ☐ Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).

* Certified copies not received: _____.

Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.

THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.

4. ☐ A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.
5. ☐ CORRECTED DRAWINGS (as "replacement sheets") must be submitted.
- (a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached
- 1) ☐ hereto or 2) ☐ to Paper No./Mail Date _____.
- (b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date _____.
- Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).
6. ☐ DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.

Attachment(s)

1. ☒ Notice of References Cited (PTO-892)
2. ☐ Notice of Draftsperson's Patent Drawing Review (PTO-948)
3. ☐ Information Disclosure Statements (PTO/SB/08), Paper No./Mail Date _____
4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material
5. ☐ Notice of Informal Patent Application
6. ☐ Interview Summary (PTO-413), Paper No./Mail Date _____
7. ☐ Examiner's Amendment/Comment
8. ☒ Examiner's Statement of Reasons for Allowance
9. ☐ Other _____.

DETAILED ACTION

Response to Amendment

1. Applicant's amendment filed on 7/27/07 has been entered.

In response to applicant's amendment and persuasive arguments, all the prior art rejection has been withdrawn.

Claims 4,6-8,10-12 and 14 are canceled.

Claims 1- 3, 5, 9, 13,15- 28 are pending in the application.

Response to Arguments

2. Applicant's arguments filed on 7/27/07 have been fully considered and are persuasive see remarks on page 10 with respect to claims 1-3,5,9,15-16, 19-28 under 103(a) rejection are withdrawn and all the pending claims 1- 3, 5, 9, 13,15- 28 are allowed.

Drawings

3. The Examiner has approved drawings filed on 8/6/03.

Reasons For Allowance

4. The following is an examiner's statement of reasons for allowance:

Claims 1- 3, 5, 9, 13,15- 28 are allowed, and renumbered as 1-20.

Applicant's arguments see page 10, lines 17- 18, page 12, and lines 4-11, of the remarks filed on 7/27/07. The prior art of record Langley (US.6,424,733 B2) discloses a multi-chamber cluster tools for inspecting wafers. Cluster tool including an adjacent inspection station for inspecting a wafer within the inspection station on a chuck following processing in a process chamber. The inspection stations equipped with a

light source, preferably a laser, stationary positioned above the wafer which is positioned on a rotatable chuck within the inspection chamber, and a light receiver stably positioned above the wafer for receiving light reflected from the wafer within the inspection chamber (i.e., at an angle about 45 degrees from perpendicular of the wafer (see light beams 44, 50; Figure 1). Langley fails to "said camera mounted on a camera support, said camera support adapted to horizontally bi-directionally move within said inspection chamber and said transfer chamber to position said camera to view the interior of the at least one process chamber." Madan et al. (US 6,258,408). Madan discloses a flexible substrate system that may be processed in a circular multiple chamber vacuum deposition system where Madan et al. further discloses "while not shown, a video system is provided within centrally located vacuum chamber 22 (transfer chamber) to enable the process to be monitored from that viewpoint", Madan et al. further discloses that the centrally located vacuum chamber has bi-directionally rotatable robotic arm and viewing stations where an operator may view internal operations that are taking place within centrally located vacuum chamber. Thus, Madan discloses a video system within the centrally located vacuum chamber (for transfer of a process substrate between chamber) for viewing the transfer process, which may also be visually monitored by operator through viewing ports. Note that Madan does not disclose what the process is to be monitored i.e., whether operation of the transfer robot or any thing else. Madan nowhere discloses or suggests "a camera provided in said inspection chamber, said camera mounted on a camera support, said camera support adapted to horizontally bi-directionally move within said inspection chamber and said

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transfer chamber to position said camera to view the interior of the at least one process chamber ", as commonly included in each of the independent claim 13 and 17, the prior art of record fails to teach either singularly or in combination, fails to anticipate or render the above limitations obvious. Claims 1- 3, 5, 9, 13,15- 28 are allowed.

5. Any comments considered necessary by applicant must be submitted on later than the payment of the issue fee and to avoid processing delays should preferably accompany the issue fee. Such submissions should be clearly labeled, comments on statement of reasons for allowance.


Contact Information

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Sheela C Chawan whose telephone number is. 571-272-7446. The examiner can normally be reached on Monday - Thursday 7.30 - 6.00.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Eileen Lillis can be reached on 571-272-6928. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Sheela Chawan
Patent Examiner
Group Art Unit 2624
July 28, 2007


SHEELA CHAWAN
PRIMARY EXAMINER